

Attorney Docket No. 5649-1286

PATENT

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Inter  
with  
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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re: Ki-yeon Park et al.

Confirmation No.: 5520

Serial No.: 10/828,596

Examiner: Ori Nadav

Filed: April 21, 2004

Group Art Unit: 2811

For: METHODS OF FORMING METAL THIN FILMS, LANTHANUM OXIDE FILMS  
AND HIGH DIELECTRIC FILMS FOR SEMICONDUCTOR DEVICES USING  
ATOMIC LAYER DEPOSITION

November 13, 2007

Mail Stop AF  
Commissioner for Patents  
P. O. Box 1450  
Alexandria, VA 22313-1450

**AMENDMENT AFTER FINAL**

Sir:

The present Amendment is being filed to address the issues raised in the final Office Action dated September 11, 2007.

It is not believed that an extension of time and/or additional fee(s)-including fees for net addition of claims-are required, beyond those that may otherwise be provided for in documents accompanying this paper. In the event, however, that an extension of time is necessary to allow consideration of this paper, such an extension is hereby petitioned under 37 C.F.R. §1.136(a). Any additional fees believed to be due in connection with this paper may be charged to our Deposit Account No. 50-0220.

**Amendments to the Claims** begin on page 2 of this paper.

**Remarks** begin on Page 12 of this paper.